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Controlling polarization and phase of high-order harmonics with a plasmonic metasurface

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1. Design of rectangular nano-antenna arrays.

Figure S1, shows the sketch of rectangular antennas, placed on 500 nm thick silicon film on sapphire substrate. The arrays of these antennas are symmetric in x and y axes. A unit cell of 450×450 nm² with periodic boundary conditions in x and y planes, and perfectly matched layer in z-plane are simulated by solving Maxwell's equations numerically, using the finite difference time domain method from Lumerical® with a mesh of $1\times1\times1$ nm³. Two plane-waves with orthogonal polarization with a relative phase-delay of 90° having an electric field magnitude of 1 V/m, located inside sapphire substrate, illuminates the arrays from below at normal incidence. The refractive indices of sapphire, silicon and gold were obtained from Palik's material data [1]. The individual rectangular antenna was 195 nm long, 80 nm wide and 20 nm thick with a gap of 30 nm. The transmittance (T) (4 μ m above the antennas) and reflectance (4 μ m below the antennas) were computed as a function of wavelength at reference planes. The total absorptance (A) was calculated according to this relation: A = 1 - T - R.

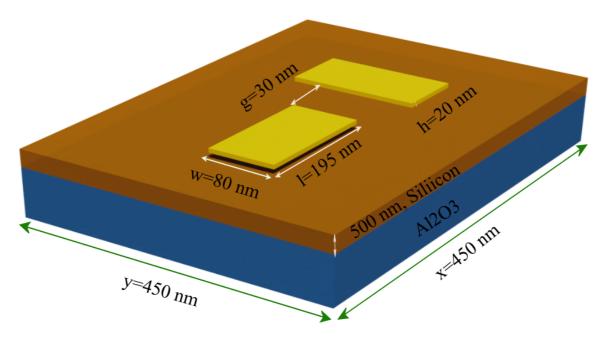


Fig. S1. The geometry of the unit cell of the simulated structure. The perpendicular rectangular antennas are placed on 500 nm thick silicon film, on sapphire substrate. A circularly-polarized light is shined from below through sapphire substrate.

Figure S2 (panel a) shows the absorptance as a function of the wavelength calculated using the above equation from the unit cell with geometrical parameters shown above. The spatial magnitude of electric field distribution of the enhancement along a cut 5 nm below the Si surface is plotted in Figure S2 (panel b), for circular polarization. Enhancement is achieved when circular polarization is parallel to the major axis of the antennas. The excitation of a surface plasmon polariton mode of the nano-antennas converts far-field radiation into intense localized near-fields which enhance high harmonic generation.

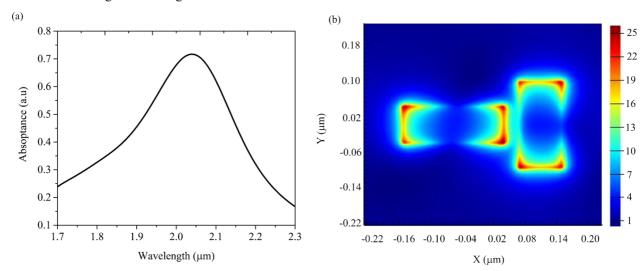


Fig. S2. (a) The absorptance as a function of wavelength is obtained from the reflectance and transmittance monitors. (b) The magnitude of electric field in the x-y plane 5 nm inside Silicon, for perpendicular antennas of dimensions L= 195 nm, W=80 nm, gap=30 nm, pitch=450 ×450 nm², at $\lambda = 2050$ nm, which is the resonance wavelength (a).

2. Fabrication of the nanoantenna arrays.

Figure 2 (inset) shows a scanning electron image of a nano-antenna array, wherein orthogonal rectangular antennas are fabricated by electron-beam lithography followed by metal evaporation and lift-off on the surface of a 500-nmthick single-crystal silicon film. Several arrays (70×70 µm² area) of perpendicular nano-antennas are fabricated to ensure that the optimal dimensions required at the resonant wavelength are met for a subset of these arrays. The silicon film is grown on an R-plane 500-nm-thick sapphire substrate (MTI Corp.). Diced chips are cleaned using acetone and IPA, and then blow-dried using nitrogen. A 2% weight PMMA in anisole solution, with a molecular weight of 450k, is used for the bottom resist layer. The diced samples are spin-coated at 5000 rpm for 60 seconds with an acceleration of 1000 rps, and then baked at 180 °C for 30 minutes, which resulted in a 50-nm-thick bottom resist layer. Similarly, a 2% wt PMMA in anisole solution, with a molecular weight of 950k, is used for the top resist layer. The top layer is spin-coated at 7000 rpm for 60 seconds, with an acceleration of 300 rps, which resulted in a 25-nm-thick top resist layer. A bilayer resist stack is used to create a re-entrant profile ensuring clean lift-off of the metal features. The nanoantennas are patterned by electron-beam lithography with a dose of 360 µCcm⁻². The samples are developed in MIBK/IPA 1:3 at 20 °C for 60 seconds. A 0.5 nm-thick titanium adhesion layer is deposited directly on the substrate followed by the evaporation of 20 nm of gold, both using electron-beam evaporation. As a final fabrication step, the metal lift-off takes place in an acetone bath at room temperature, which is sonicated at 30 kHz for 30 seconds and followed by blow-dried using nitrogen.

3. Measuring the Stokes parameters by rotating quarter-waveplate (λ /4) method.

In order to confirm that the generated harmonics are circularly-polarized rather then unpolarized, we adopted the rotating quarter wave plate method [2] to retrieve the Stokes parameters for the 5^{th} harmonic. For this purpose, we used a $\lambda/4$ waveplate and a polarizer after the sample and measured the harmonic intensity of HH5 as a function of

the waveplate angle. A plot of the measured HH5 intensity as a function of the waveplate angle, θ , is shown in **Figure S3**.

The intensity of the harmonic beam I_n that is transmitted through the waveplate-polarizer combination for each waveplate angle θ_n , can be written as [2]:

$$I_n = \frac{1}{2}(A + B\sin 2\theta_n + C\cos 4\theta_n + D\sin 4\theta_n)$$
 $(n = 1, 2, 3...N)$ (1)

The coefficients A, B, C and D are determined using:

$$A = \frac{2}{N} \sum_{n=1}^{N} I_n \; , \; \; B = \frac{4}{N} \sum_{n=1}^{N} I_n \sin 2\theta_n \; , \; \; C = \frac{4}{N} \sum_{n=1}^{N} I_n \cos 4\theta_n \; , \; D = \frac{4}{N} \sum_{n=1}^{N} I_n \sin 4\theta_n \;$$

By substituting the experimental harmonic intensities I_n into (2), we obtain the values of the coefficients A = 3689.067, B=-3551.469, C= -442.142, and D= 297.220.

The Stokes parameters are found to be:

$$S_0 = A - C$$
, $S_1 = 2C$, $S_2 = 2D$, $S_3 = B$.

This procedure yields the normalized Stokes vector as:

$$S = \begin{pmatrix} 1 \\ -0.214 \\ 0.144 \\ -0.860 \end{pmatrix}$$

This confirms that HH5 is 90% polarized, and is primarily left circularly polarized.

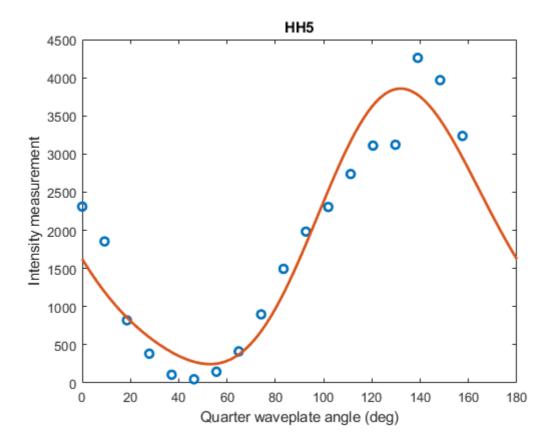


Fig. S3. Measured intensity of HH5 after passing through a polarization analyzer composed of a quarter waveplate and a linear polarizer, as a function of the angle of the quarter waveplate (circles). The line is a fit to the data using eqs. 1 and 2.

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